



Advances in Manufacturing, Characterization and Applications of Functional Micro/Nano Structured Surfaces

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Deadline for manuscript
submissions:
closed (30 April 2024)

Message from the Guest Editors

Dear Colleagues,

We are pleased to invite you to publish your original research findings in this Special Issue entitled “Advances in Manufacturing, Characterization and Applications of Functional Micro/Nano Structured Surfaces”.

This Special Issue aims to seek recent advances in novel and state-of-the-art research and development within the field of advanced manufacturing and characterization technologies of functional micro-/nanostructured surfaces, as well as their applications. In addition, multidisciplinary (physiochemical, micro-/nano- and biomedicine) manufacturing technologies and characterization methods are welcome across all types of papers, such as original research papers and review articles.

We look forward to receiving your contributions to the Special Issue.





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Editor-in-Chief

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Message from the Editor-in-Chief

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